

HIGH CONDUCTIVITY OF SI-DOPED B-(ALXGA1-X)2O3 THIN FILMS VIA MIST CVD

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Recently, gallium oxide (Ga₂O₃) has gained attentions for power switching applications owing to its high breakdown field [1]. β-(Al_xGa_{1-x})₂O₃, an alloy of β-Ga₂O₃ and θ-Al₂O₃, is essential for Ga₂O₃-based heterojunction device applications [2]. For β-Ga₂O₃, Si is utilized as the most effective n-type dopant [3]. Our group has reported high-conductivity Si-doped β-Ga₂O₃ thin films via mist CVD, which can be performed cost-friendly [4]. Therefore, we demonstrated Si-doped β-(Al_xGa_{1-x})₂O₃ thin films via mist CVD to enhance the Ga₂O₃-based device applications.

We utilized Ga(acac)₃, Al(acac)₃, and C₆H₁₂ClNSi as mist CVD precursors. Si-doped β-(Al_xGa_{1-x})₂O₃ thin films were grown on Fe-doped β-Ga₂O₃(010) substrates by mist CVD.

Figure 1 shows (a) X-ray diffraction (XRD) 2θ-ω scan profiles, (b) reciprocal space mapping (RSM), and (c) the relationship between the Hall mobility and carrier concentration of the Si-doped β-(Al_xGa_{1-x})₂O₃ thin films for Al compositions below 10% and above 10%. As shown in Fig. 1(a), the peak of the highly crystalline β-(Al_xGa_{1-x})₂O₃ 020 with Laue oscillation was observed. RSM revealed that the thin film was coherently grown on the substrate. The Al composition was calculated from the peak of XRD 2θ-ω following the report by Oshima et al. [5] The mobility decreases as the Al composition exceeds 10%. This result is consistent the findings of Anhar Uddin Bhuiyan et al. [6] In addition, highly conductive β-(Al_{0.14}Ga_{0.86})₂O₃ thin films which exhibits 593 S/cm were achieved through Si doping by mist CVD.

These results are expected to expand possibility of Ga₂O₃-based device applications.